

In re application of

Kazuhiko NAGANO, et al.

Appln. No.: 10/074,258 Group Art Unit: NOT YET ASSIGNED

Confirmation No.: 5060 Examiner: NOT YET ASSIGNED

Filed: February 14, 2002

For: OPTICAL MODELING DEVICE AND EXPOSURE UNIT

PRELIMINARY AMENDMENT

Commissioner for Patents Washington, D.C. 20231

Sir:

Prior to examination, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 2, Please delete the first full paragraph and replace with the following new paragraph:

A conventional optical modeling device used for such an optical modeling system is divided into a laser plotter type optical modeling device using a laser plotter for scanning and a movable mirror type modeling device using a movable mirror for scanning. Both types of the optical modeling devices can be referred to an issue titled, Maruya, Yoji. 1992. Hikari zokei shisutemu no kiso, genjou, mondaiten. (Foundation, status quo, and issues in optical molding systems technology.) Kata Gijutsu (Die and Mold Technology) 7, no. 10:18-23.